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BIB DATA SHEET

CONFIRMATION NO. 6363

JAPAN 2003-430954 12/25/2003 JAPAN 2004-344150 11/29/2004 ** IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 07/28/2008											
RULE APPLICANTS Toshihisa Nozawa, Hyogo-Ken, JAPAN; Koji Kotani, Hyogo-Ken, JAPAN; Koji Kotani, Hyogo-Ken, JAPAN; This application is a 371 of PCT/JP2004/019406 12/24/2004 **FOREIGN APPLICATIONS JAPAN 2003-430954 12/25/2003 JAPAN 2004-344150 11/29/2004 **IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 07/28/2008 ** STATE OR SHEETS TOTAL INDEPENDENT CLAIMS TOTAL CLAIMS			FILING or 371(c) DATE			GR	ROUP ART UNIT				
APPLICANTS Toshihisa Nozawa, Hyogo-Ken, JAPAN; Koji Kotani, Hyogo-Ken, JAPAN; Koji Kotani, Hyogo-Ken, JAPAN; **CONTINUING DATA ******* This application is a 371 of PCT/JP2004/019406 12/24/2004 **FOREIGN APPLICATIONS**** JAPAN 2003-430954 12/25/2003 JAPAN 2004-344150 11/29/2004 **IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 07/28/2008 **STATE OR COUNTRY DRAWINGS CLAIMS CLAIMS CLAIMS CLAIMS CLAIMS CLAIMS CLAIMS 2 ** ADDRESS SMITH, GAMBRELL & RUSSELL 1130 CONNECTICUT AVENUE, N.W., SUITE 1130 WASHINGTON, DC 20036 UNITED STATES TITLE Temperature Controlling Method for Substrate Processing System and Substrate Processing System All Fees In	10/583,84	17	07/15/2008		062		3744		33082M331		
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35 USC 119(g-d) conditions met											
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